34474 	Subclass	SSUE CLASSIFICATION
1c971 U	Class	ISSUE CLA



PATENT NUMBER

U.S. **UTILITY** Patent Application

O.I.P.E. PATENT DATE SCANNED TR4

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	Massacroticu ™	Marsale I					

Yoshio Hayashide

祖后

Polishing solution supply system, method of supplying polishing solution, appearatus for and method of polishing semiconductor substrate and method of manufactoric semiconductor devices.

PTO-2040 12/99

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ISSUING CLASSIFICATION						
ORIGINA	ORIGINAL CROSS REFERENCE(S)					
CLASS SUBCLASS		CLASS SUBCLASS (ONE SUBCLASS PER BLOCK)				
INTERNATIONAL	CLASSIFICATION		☐ Continued on Issue Slip Inside File Jacket			

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TERMINAL DISCLAIMER	DRAWINGS			CLAIMS ALLOWED		
	Sheets Drwg.	Figs. Drwg.	Print Fig.	Total Claims	Print Claim for O.G	
☐ The term of this patent		1		NOTICE OF ALLOWANCE MAILED		
subsequent to (date) has been disclaimed.	(Assistant	Examiner)	(Date)		•	
The term of this patent shall not extend beyond the expiration date			,			
of U.S Patent. No.				ISSUE FEE		
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WARNING:						
The information disclosed herein may be res Possession outside the U.S. Patent & Traden					Sections 122, 181 and 36	

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